

Inventor: Craig M. Carpenter; Ross S. Dando
Title: Chemical Vapor Deposition Apparatuses and Deposition
Methods
Assignee: Micron Technology, Inc.
Attorney Docket No. MI22-1563



INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

REMARKS

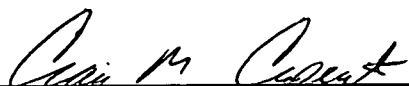
The citations listed, copies attached, may be material to the examination of the subject application and are therefore submitted in compliance with the duty of disclosure defined in 37 CFR §1.56. The Examiner is requested to make these citations of official record in this application. No admission is made regarding whether all the submitted references are prior art.

The materials cited are presented to assist in and expedite examination of this application. The present invention is considered to be patentable over the cited materials. Expeditious examination and allowance of this application as a patent are therefore urged in order that the public may benefit from the disclosure and commercialization of the invention.


EL 465855490

R spectfully submitted,

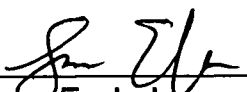
Dated: 1 MARCH 2001

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Dated: 3 March 2001

Inventor: 
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Dated: 13 Mar 2001

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1563	SERIAL NO. Filed Herewith			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Craig M. Carpenter; Ross S. Dando				
				FILING DATE Filed Herewith	GROUP Unknown			
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
/KMS/	AA	5,983,906	11/16/99	Zhao et al				
	AB							
	AC							
	AD							
	AE							
	AF							
	AG							
	AH							
	AI							
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FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AR							
	AS							
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EXAMINER /Kelly Stouffer/				DATE CONSIDERED 01/10/2008				
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								

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